

ABSTRACT OF THE DISCLOSURE

5 An opening/closing of a plurality of valves are controlled so that a plurality of gases flow into a chamber in an operation of a semiconductor manufacturing apparatus, and the opening/closing of the plurality of valves are controlled so that a gas A flows into mass flowmeters in an inspection of a mass flow controller MFC 2'. Therefore, the inspection can be achieved while maintaining the connection of mass flow controller MFC 2' to the semiconductor manufacturing apparatus.